

**Abstract**

An optical MEMS devices is imaged to a different location at which a second optical MEMS device is located in a manner that effectively combines the tilt angles of at least one micro mirror of each of the first and second optical devices. The imaging system may reproduce the angle of reflection of the light from the first micro mirror. This may be achieved using a telecentric system, also known as a 4 f system, as the imaging system. The physical size of the arrangement may be reduced by compacting the optical path, e.g., using appropriate conventional mirrors, and/or employing folded arrangements, i.e., arrangements in which there is only one MEMS device stage that does double duty for both input and output through the use of at least one conventional mirror.

T06290"53096B50